

# 回路のばらつき解析を用いた デバイスばらつきの抽出

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# Outline

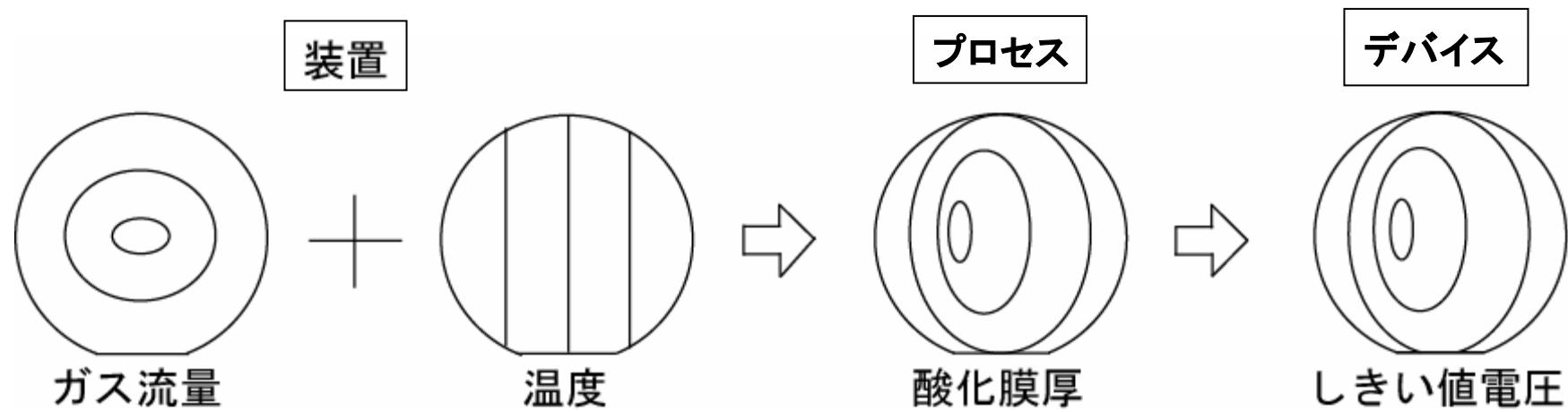
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1. Conventional circuit–variation analysis based on device/process variation
  - Corner models from device–performance variation
  - Process models from process–variation analysis
2. Requirements for more accurate prediction of circuit–performance variation
3. Separation of inter–die and random intra–die variations with appropriate circuits
4. Prediction of circuit–performance variation

# Typical variation effects

1. Systematic variation between processed lots: Inter-wafer

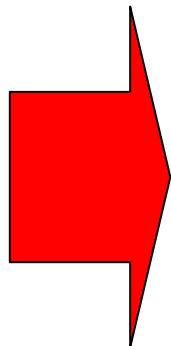
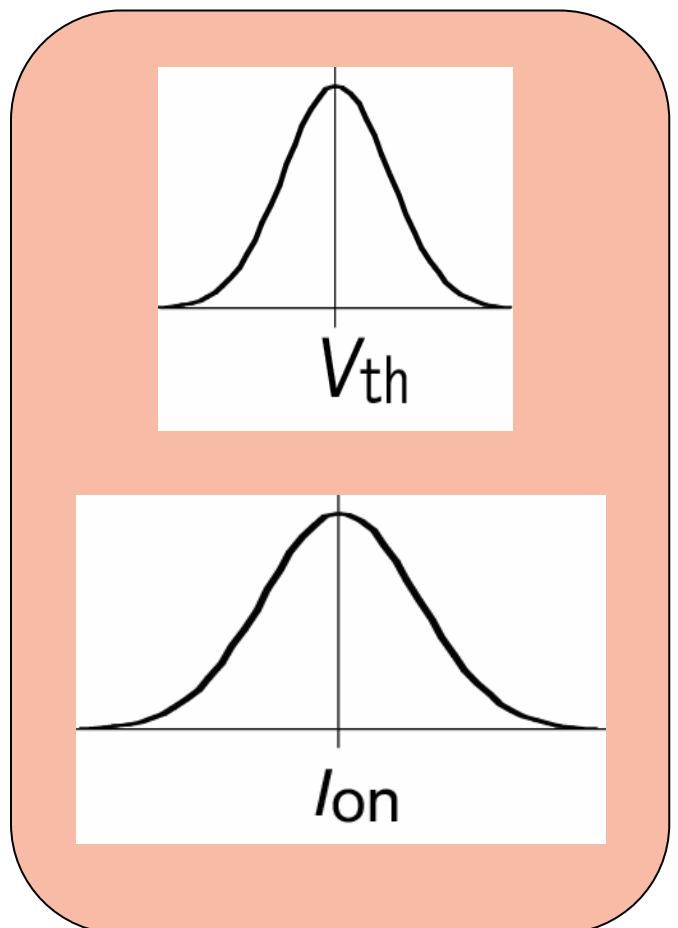
2. Parametric variation of process steps: Inter-die



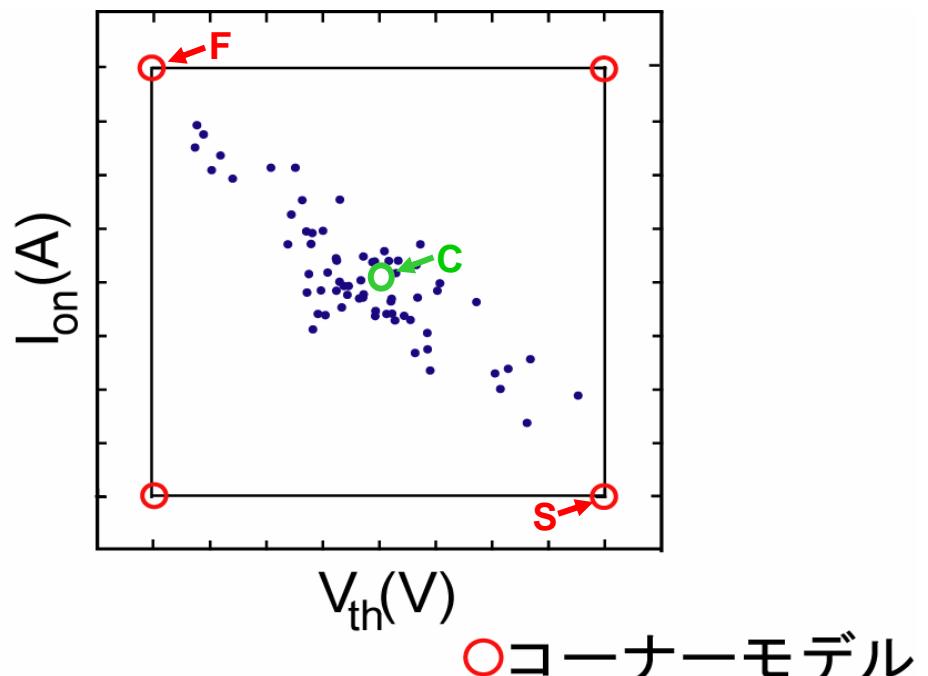
3. Random variation at close distances: Intra-die

# Method of corner models (1)

## Device variations



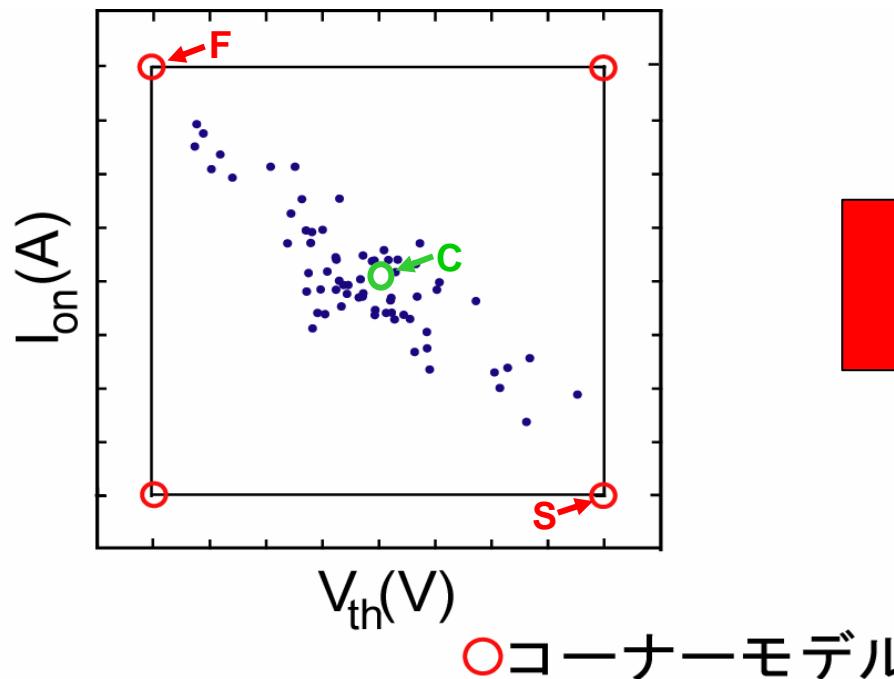
## Models for variation extremes (Corner models)



F = fast, S = slow, C = centric

# Method of corner models (2)

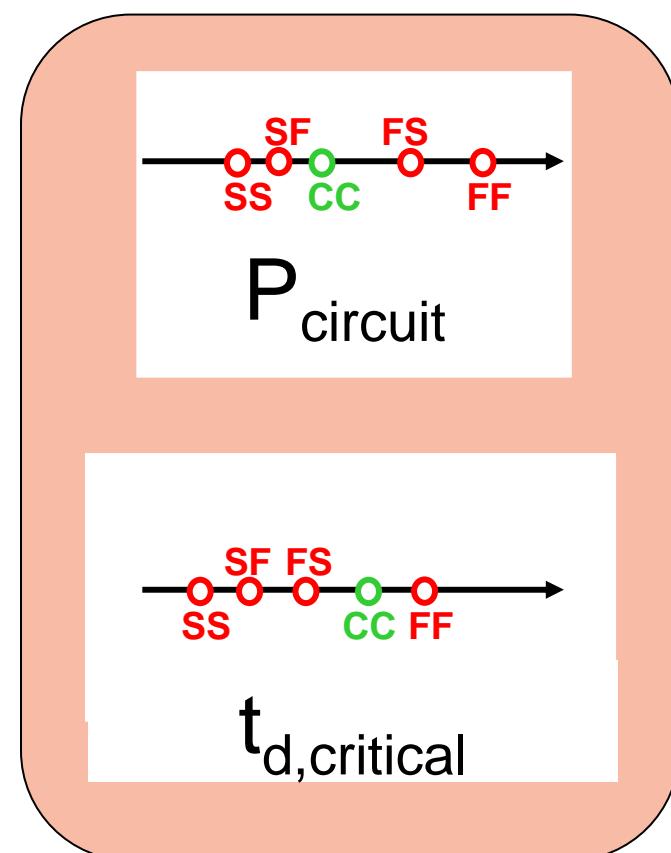
## Models for variation extremes (Corner Models)



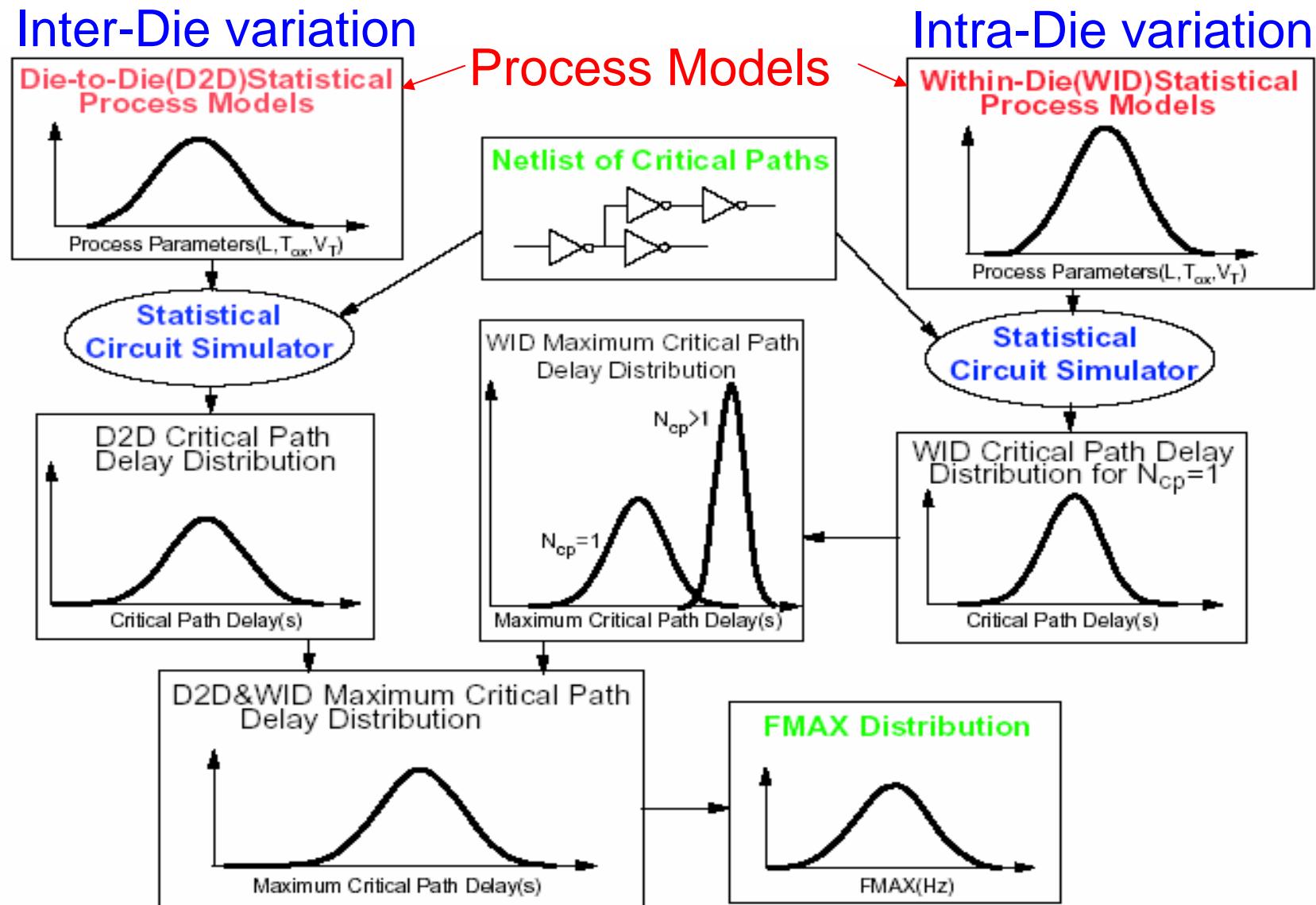
F = fast, S = slow, C = centric

Conventional corner models cover mainly inter-wafer variations and overestimates circuit-performance variation.

## Circuit variations (XX refers to nMOS and pMOS corner models)



# Process-variation-based circuit analysis



K. A. Bowman et al., IEEE J. SSC, 37, 183, 2002.

# Deficiencies process/device-based methods

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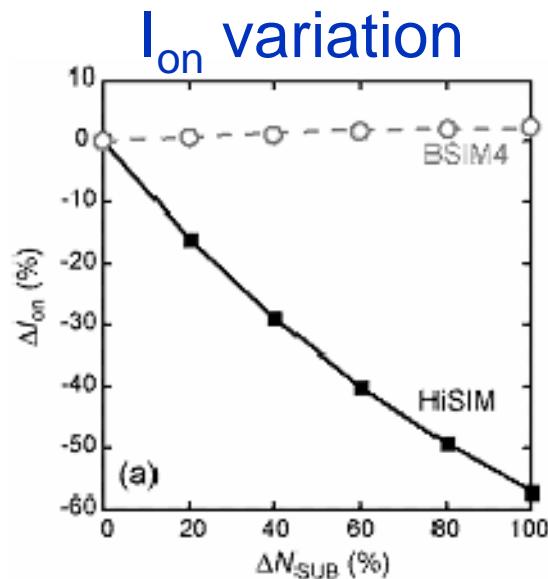
- Determination of probability distribution of circuit-performance variations from **statistical process data** is not really practical.
- Separation of inter-die and intra-die variations is difficult. Circuits relying on matching between transistors can help here.
- No **practical reverse engineering possibility** from desired circuit performance variation to necessary device-parameter variation requirements.

# Outline

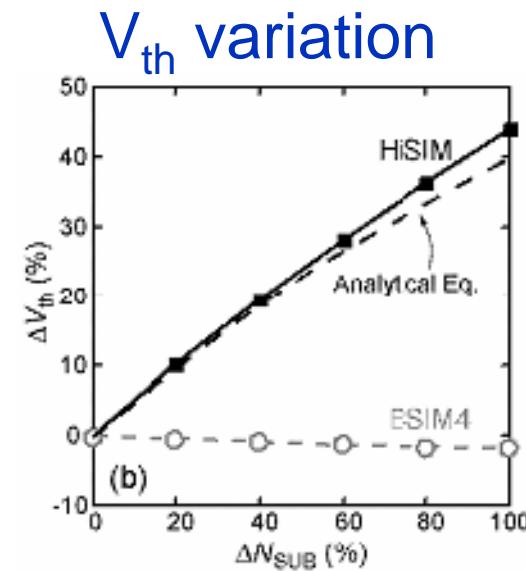
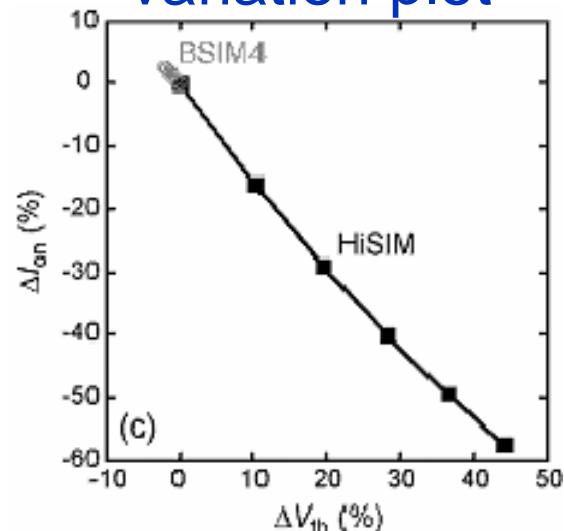
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1. Conventional circuit–variation analysis based on device/process variation
2. Requirements for more accurate prediction of circuit–performance variation
  - Compact Model with accurate device–parameter correlation
  - Knowledge of inter–wafer, inter–die and random intra–die variations
3. Separation of inter–die and random intra–die variations with appropriate circuits
4. Prediction of circuit–performance variation

# Variation modeling with compact models



Combined  $I_{on}$ ,  $V_{th}$  variation plot



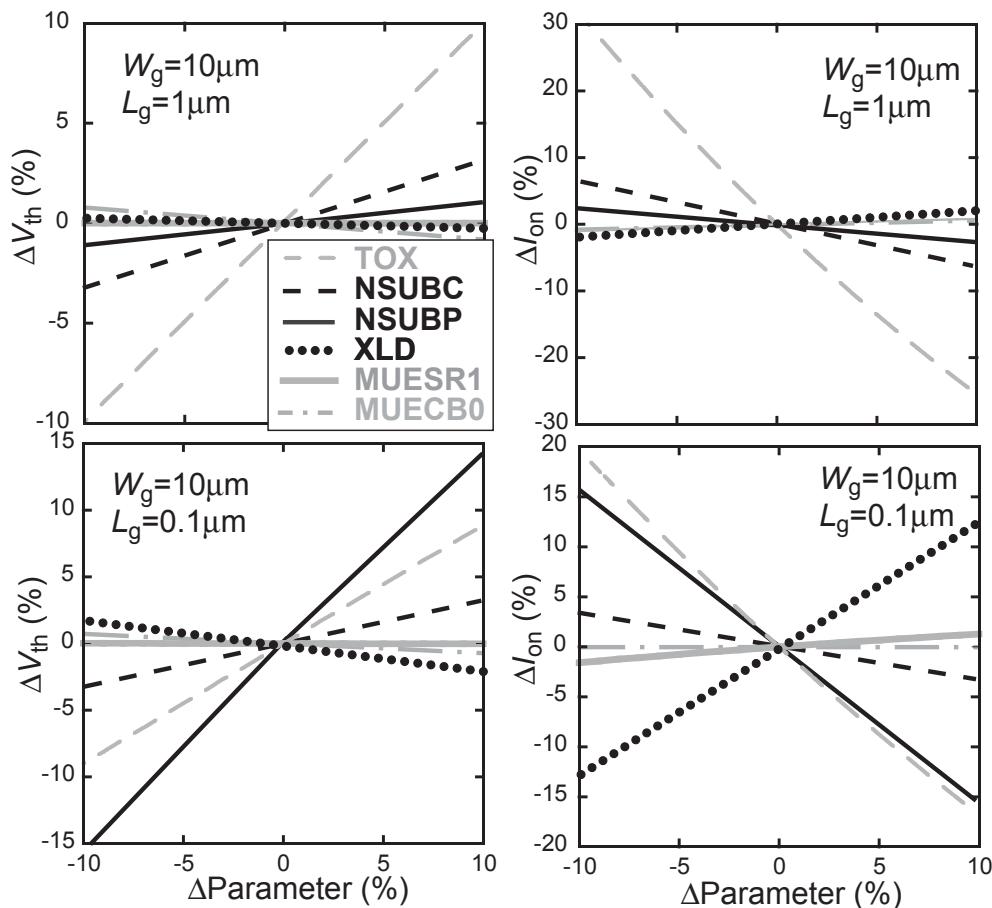
Correct correlation between device and process parameters is required.



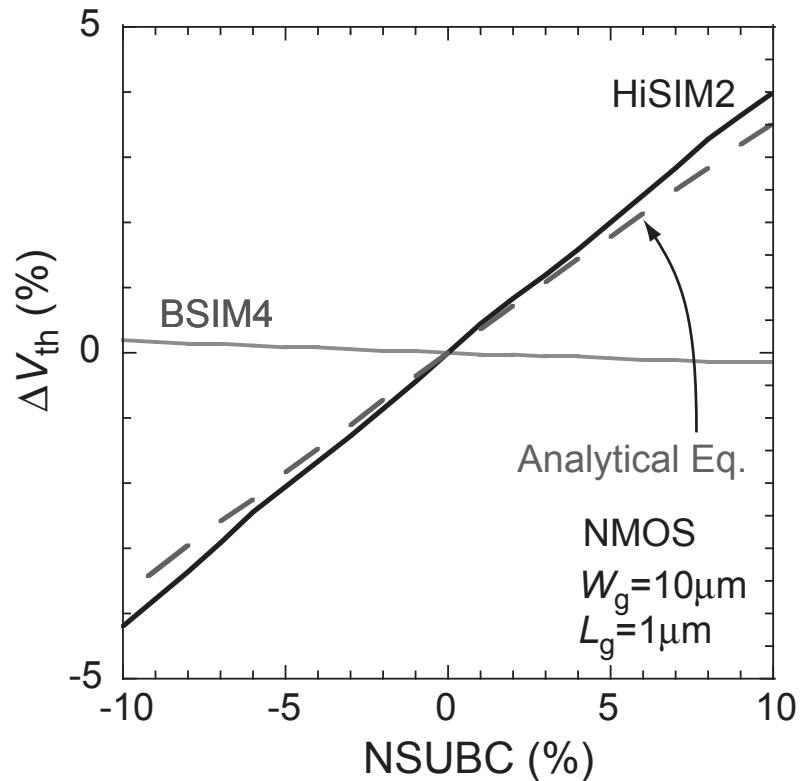
Surface-potential models like HiSIM needed.

# Sensitivity analysis for process parameters

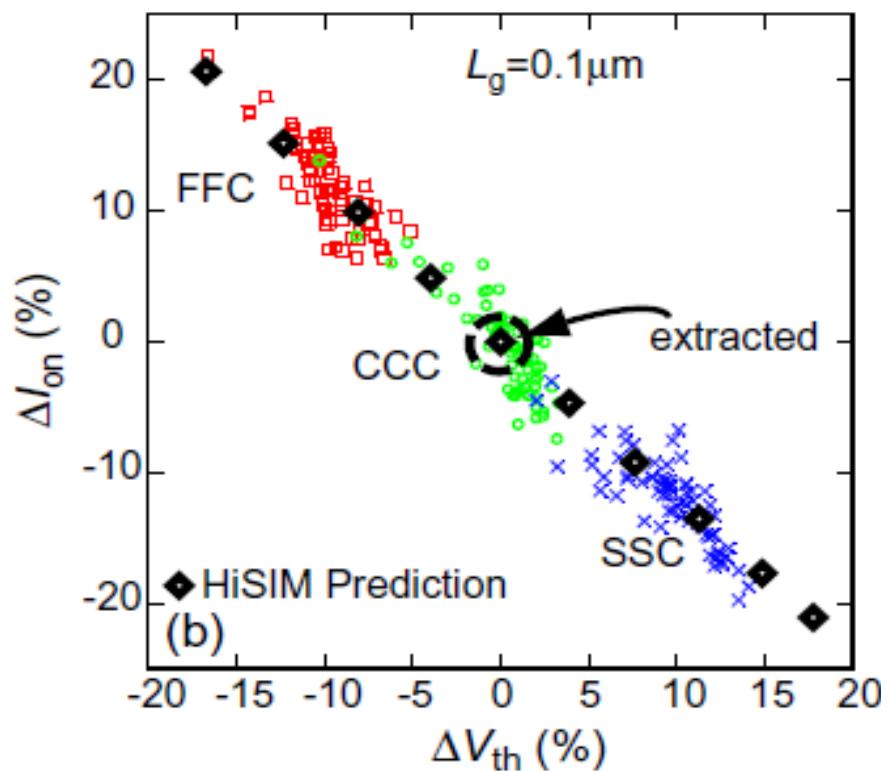
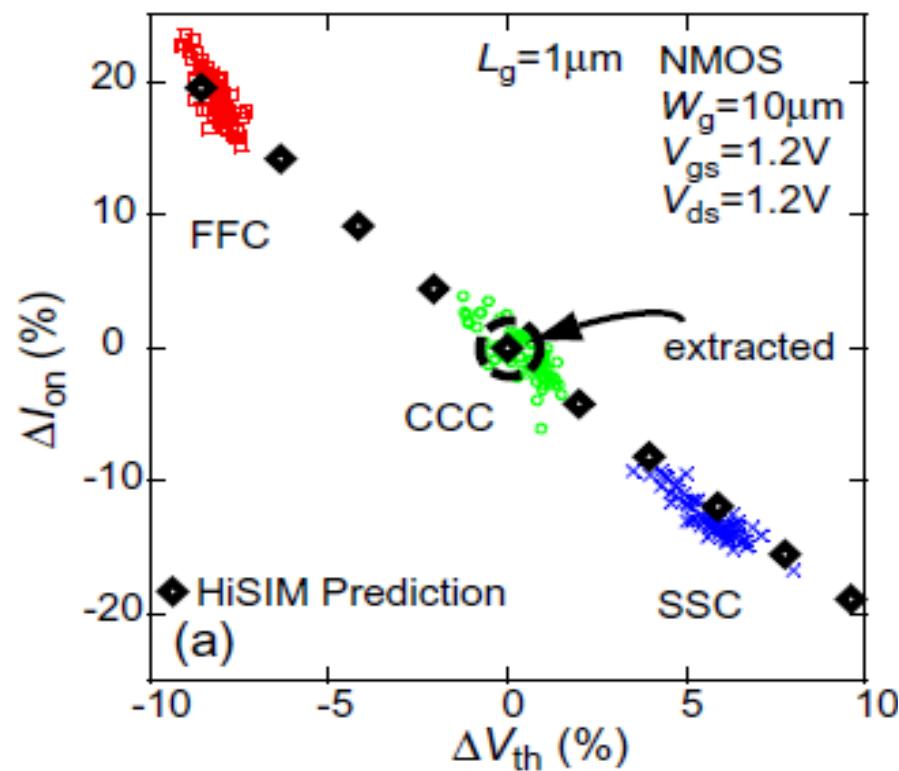
## Prediction with HiSIM



## Comparison with conventional model

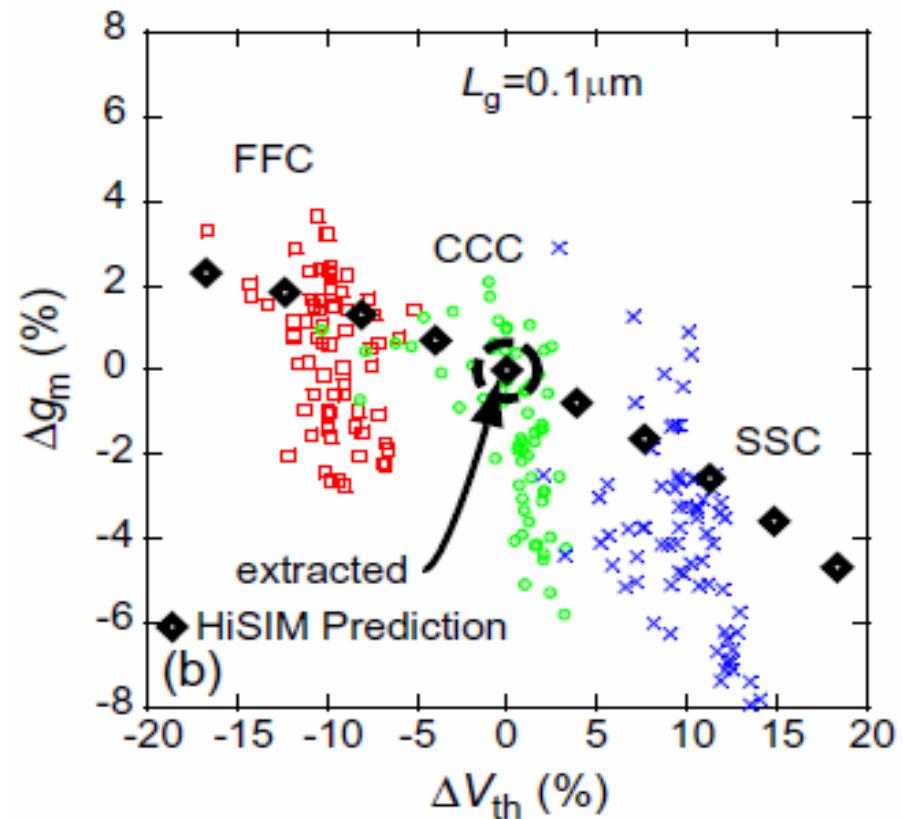
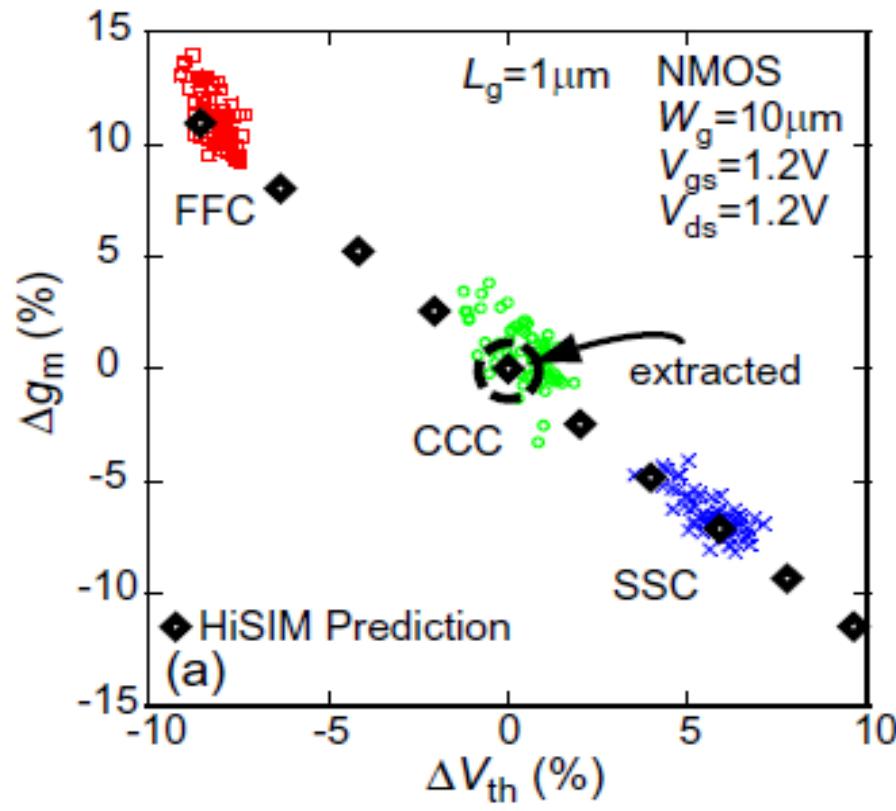


# Inter-wafer variation prediction with HiSIM (1)



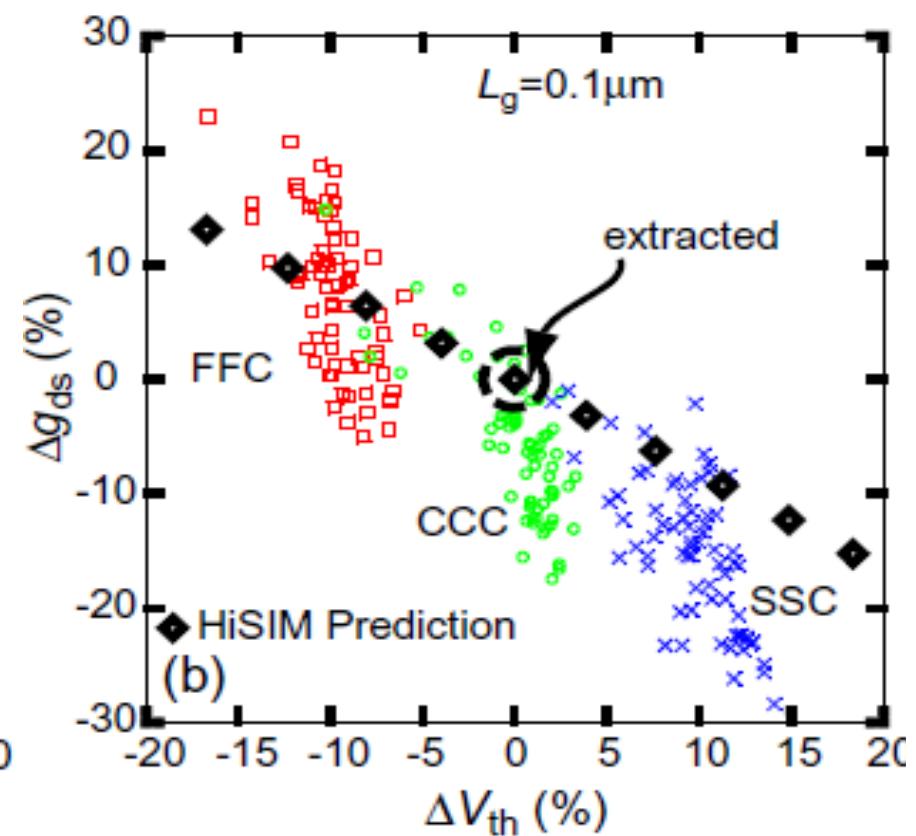
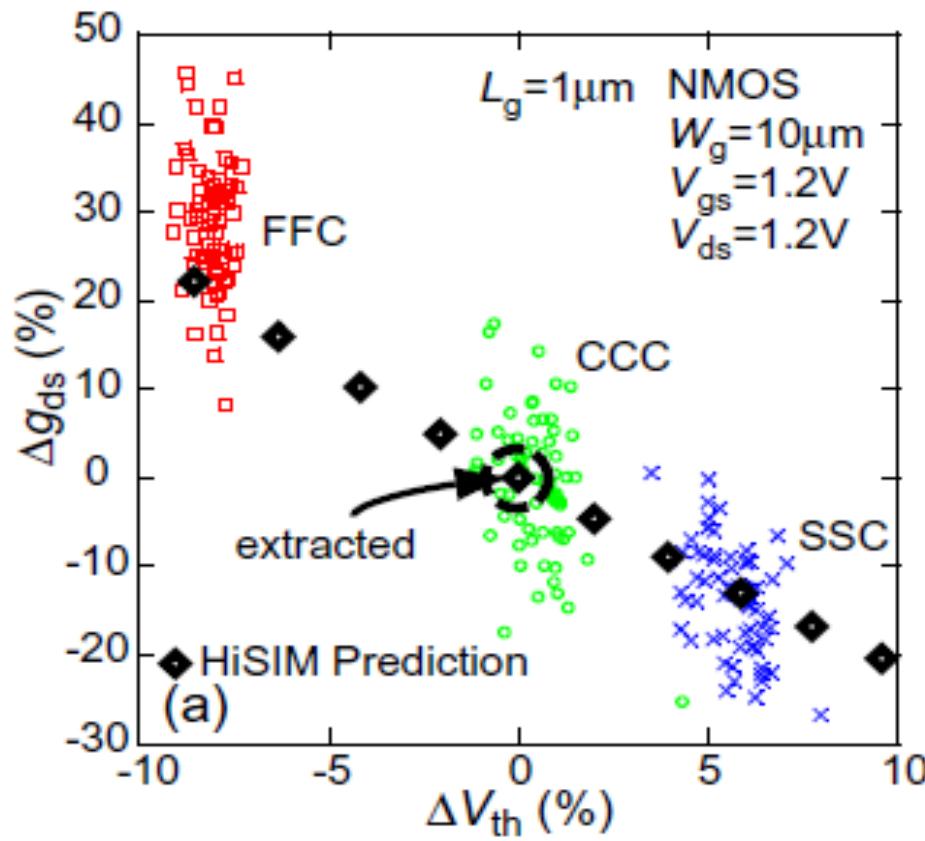
Prediction of inter-wafer variation for  $I_{\text{on}}$ ,  $V_{\text{th}}$  possible

## Inter-wafer variation prediction with HiSIM (2)



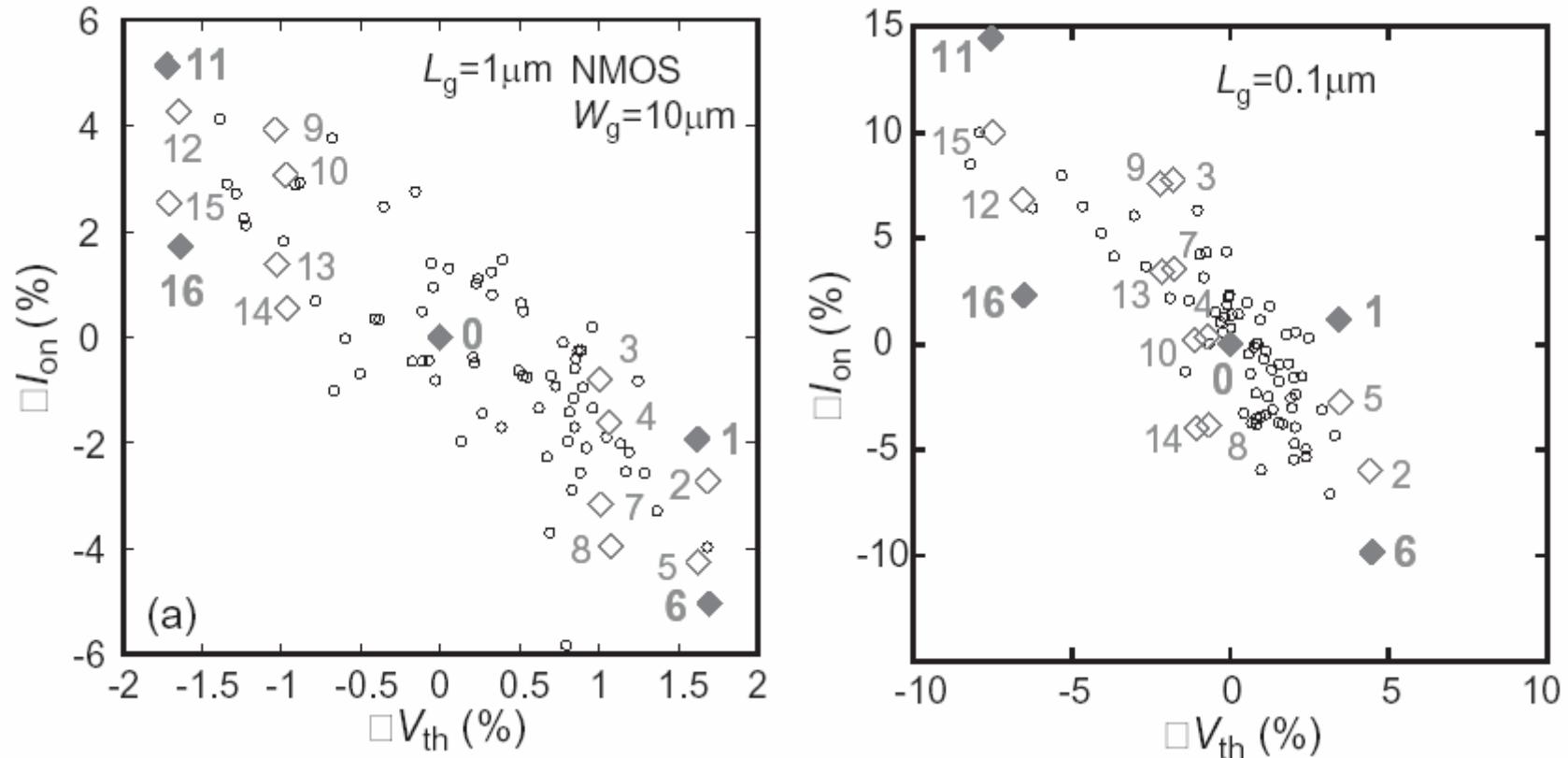
Prediction of derivative variation: Example  $g_m$

# Inter-wafer variation prediction with HiSIM (3)



Prediction of derivative variation: Example  $g_{ds}$

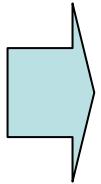
# Inter-die variation



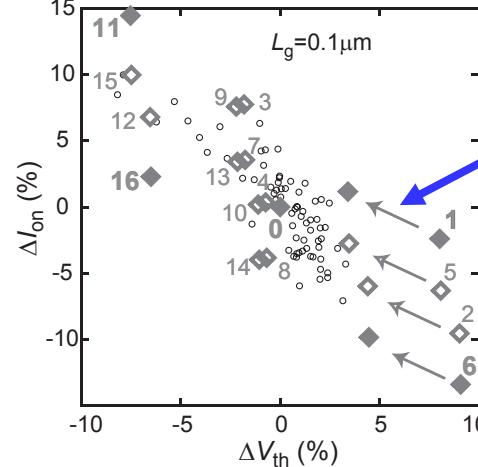
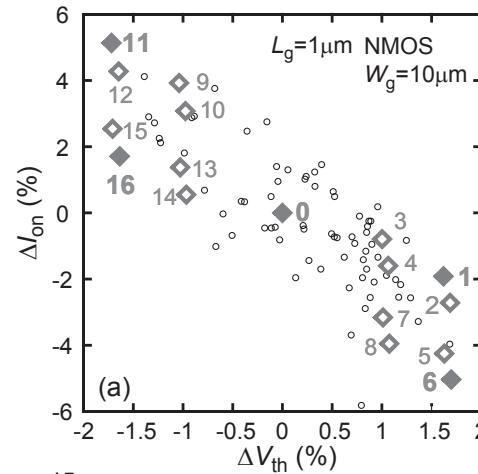
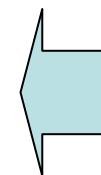
Consistent relation between inter-die device-performance variation and physical process-parameter variation can be established.

# Extraction of inter-die process variation

Index \	$\Delta NSUBC$	$\Delta MUESR1$	$\Delta NSUBP$	$\Delta XLD$
0	0	0	0	0
1	+	+	+	+
2	+	+	+	-
3	+	+	-	+
4	+	+	-	-
5	+	-	+	+
6	+	-	+	-
7	+	-	-	+
8	+	-	-	-
9	-	+	+	+
10	-	+	+	-
11	-	+	-	+
12	-	+	-	-
13	-	-	+	+
14	-	-	+	-
15	-	-	-	+
16	-	-	-	-



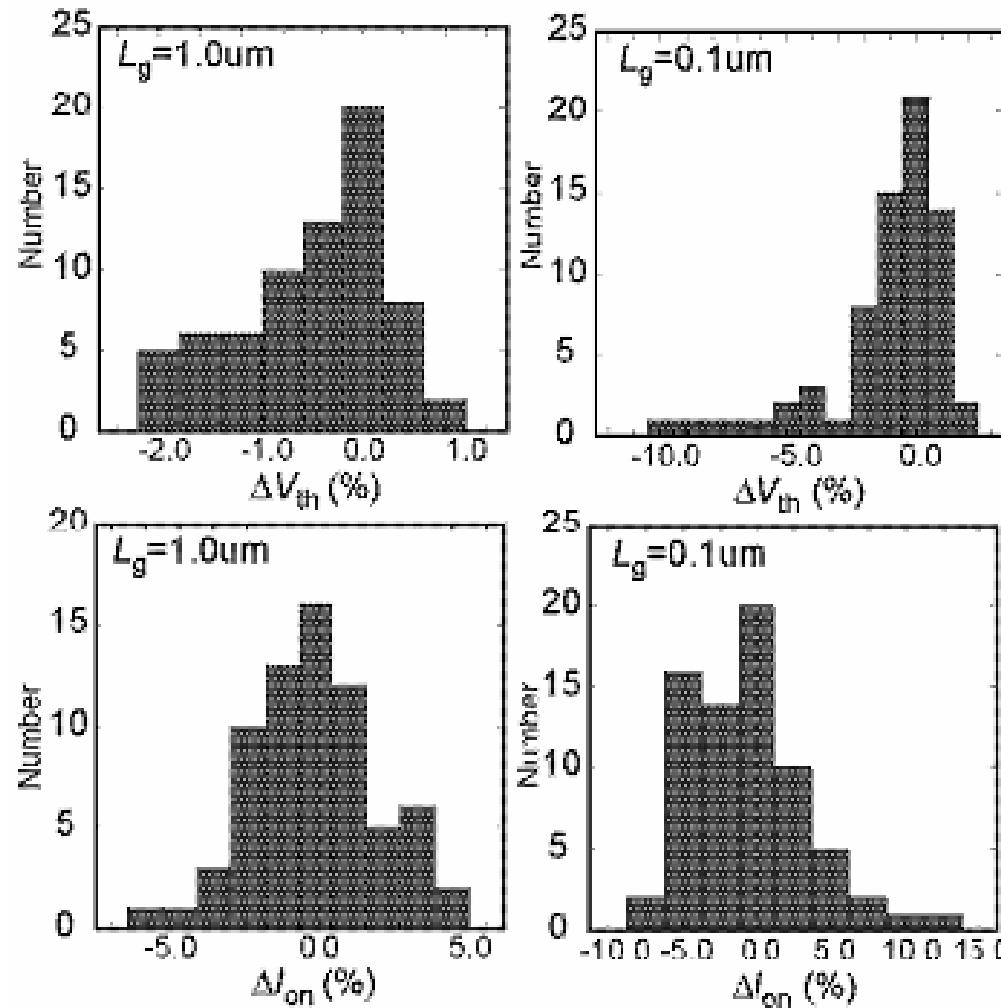
	$\Delta NSUBC$	$\Delta MUESR1$	$\Delta NSUBP$	$\Delta XLD$
Variation	$\pm 4\%$	$\pm 10\%$	$-3\%$ $+1\%$	$\pm 3\%$



Indication for asymmetric pocket-implant variation.

HiSIM enables extraction of process-parameter variation from device-performance variation.

# Asymmetric inter-die variation



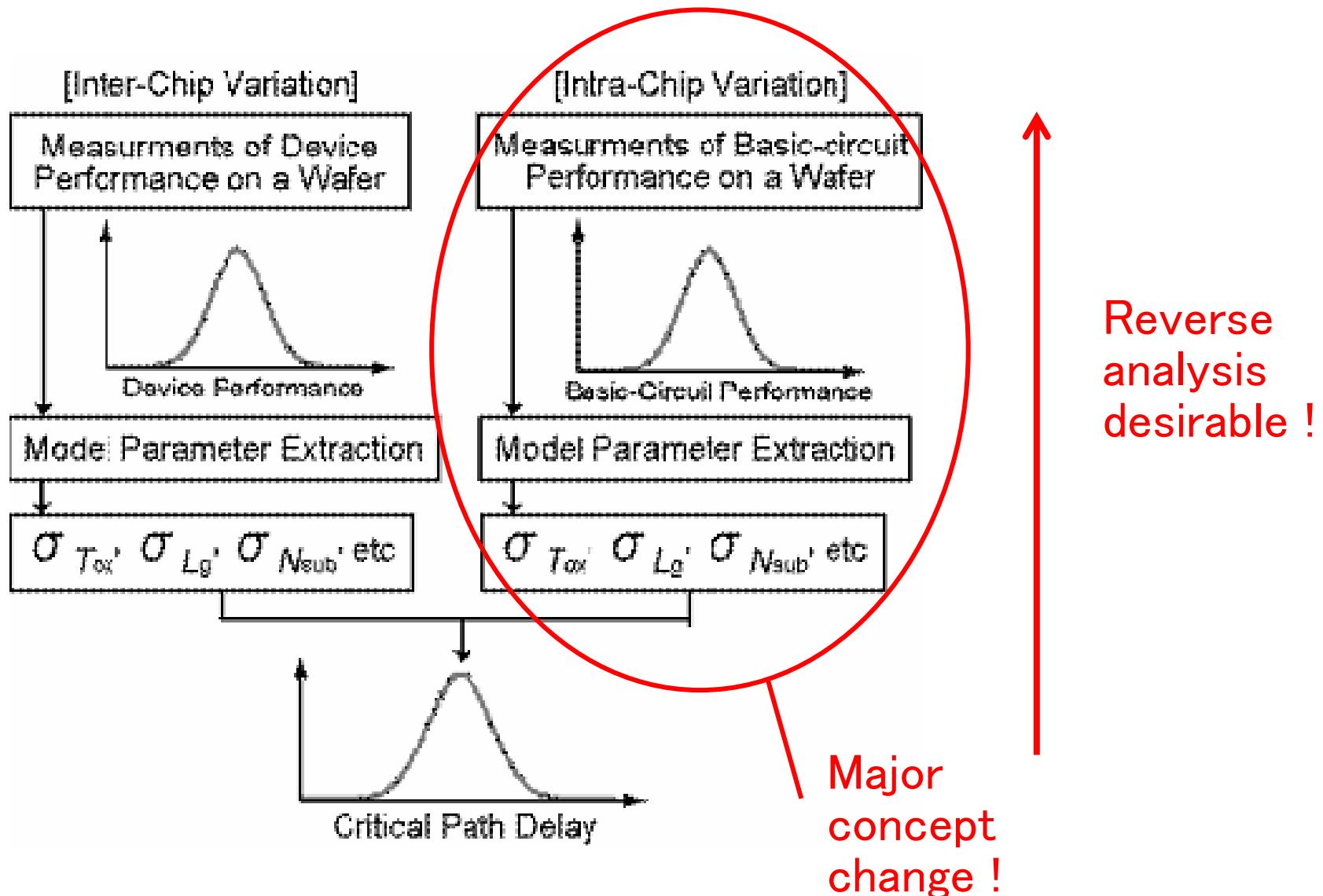
Short-channel devices show stronger asymmetry

# Outline

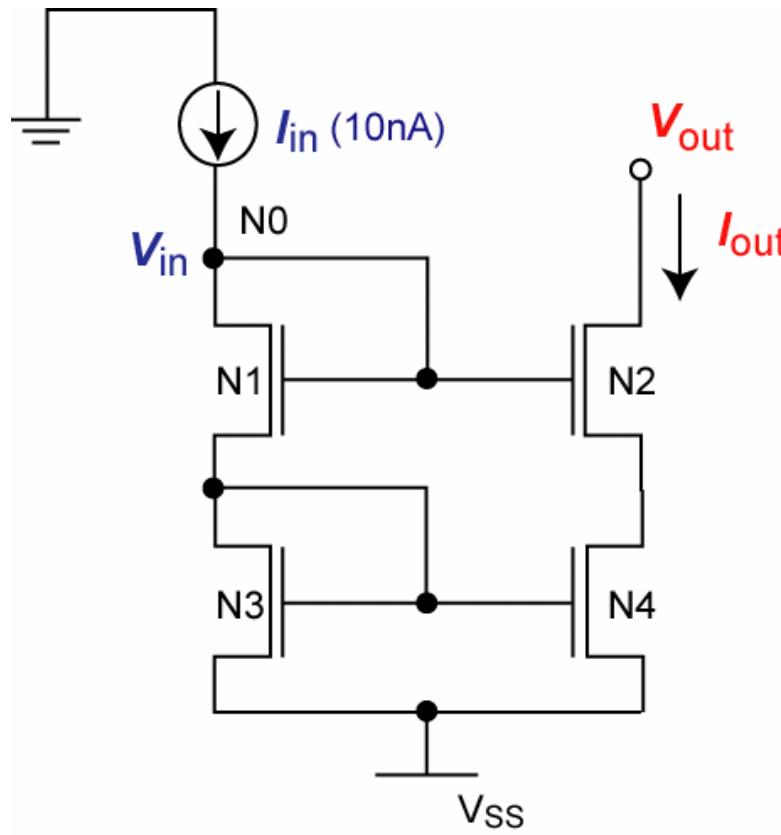
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1. Conventional circuit–variation analysis based on device/process variation
2. Requirements for more accurate prediction of circuit–performance variation
3. Separation of inter–die and random intra–die variations with appropriate circuits
  - Cascode current source
  - Differential Amplifier Stage
4. Prediction of circuit–performance variation

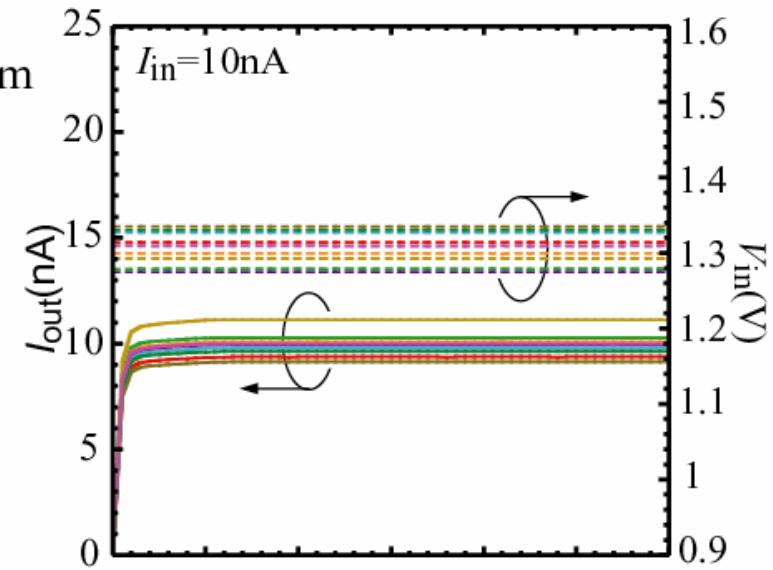
# Device and circuit based variation analysis



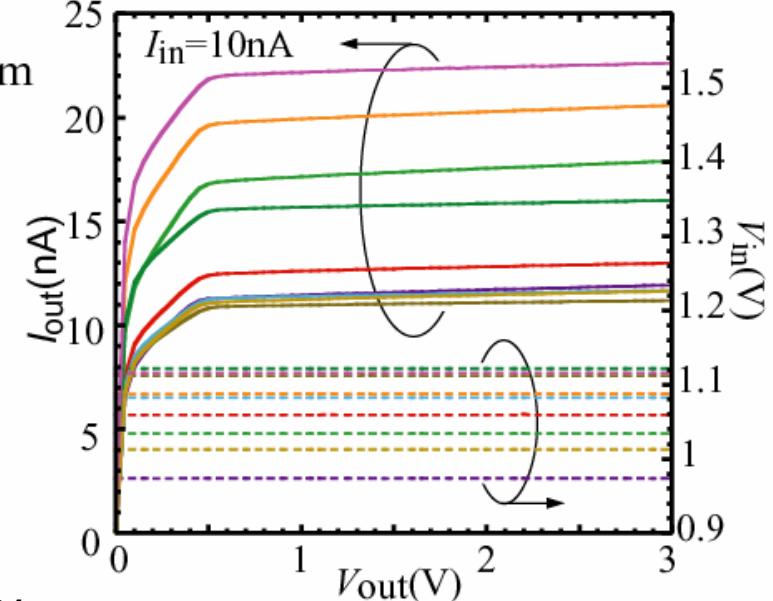
# Cascode current source



$L_{gate}=2.1\mu m$



$L_{gate}=0.6\mu m$

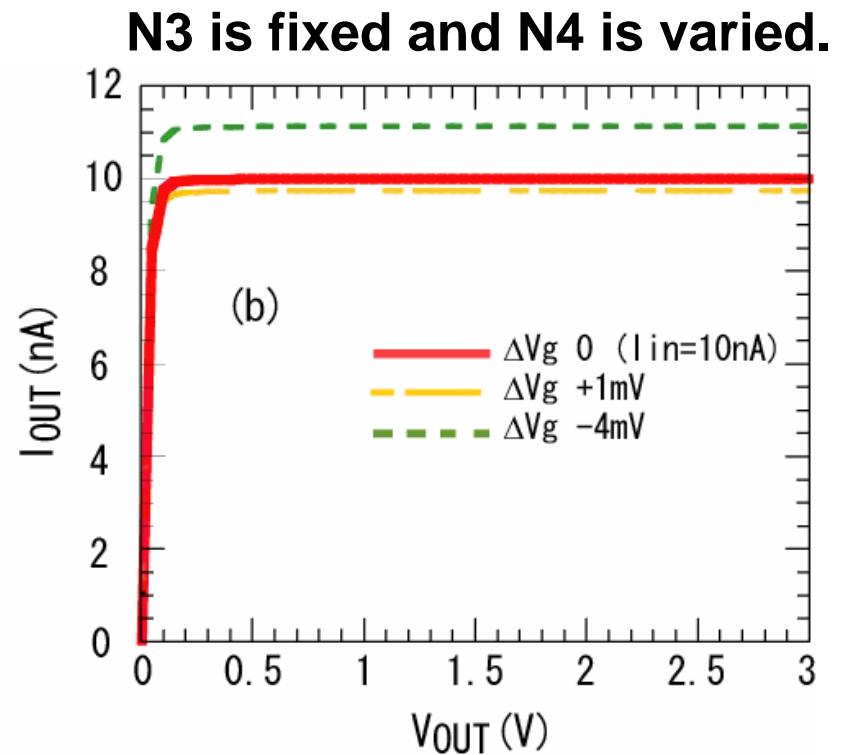
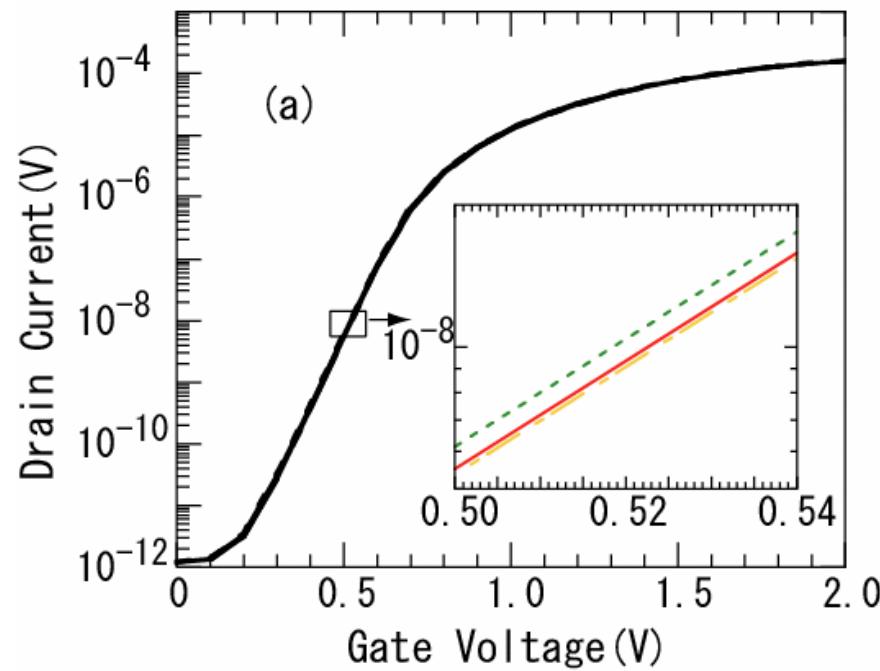


**Function:** to provide a constant current  $I_{out}$ , which is proportional to the given current  $I_{in}$  and independent of  $V_{out}$ .

$I_{in}=10nA$ : technology variation becomes evident  
resistance effects etc. are suppressed

D. Miyawaki et al., APS-DAC, p. 39, 2001.

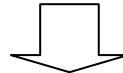
# Variation of $I_{\text{out}}$ result from N3/N4 mismatch



$I_{\text{out}}$  variation allows to determine the  $\Delta V_g$  mismatch.

# Inter- and intra-die variation separation

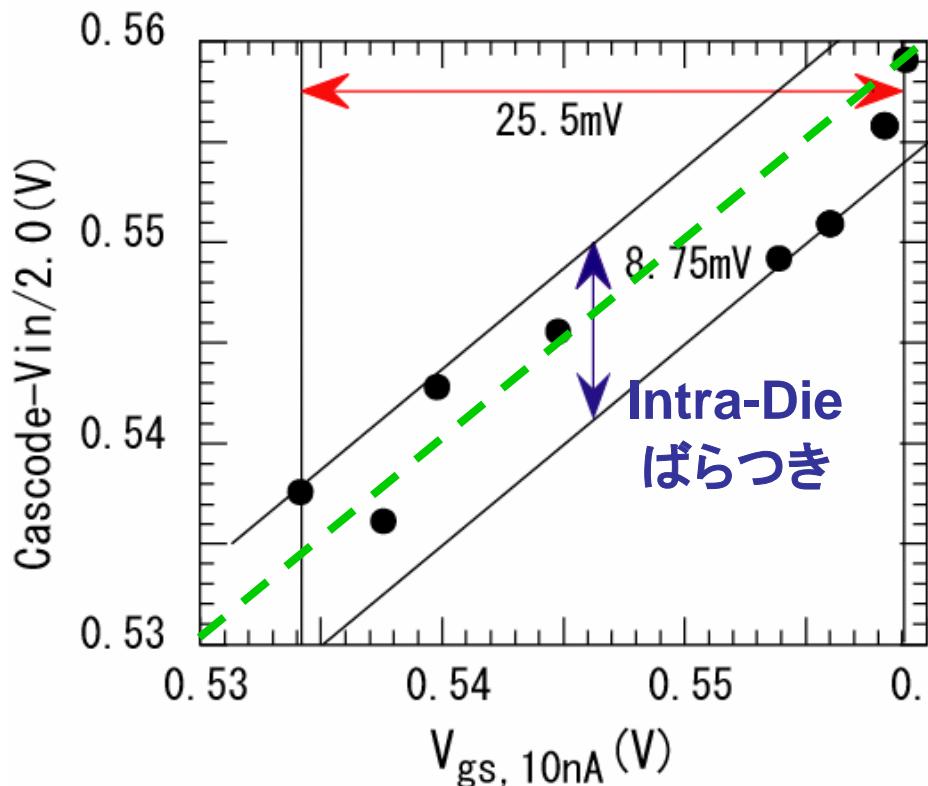
$V_{in}$  variation is determined by the combined variation of N1 and N3



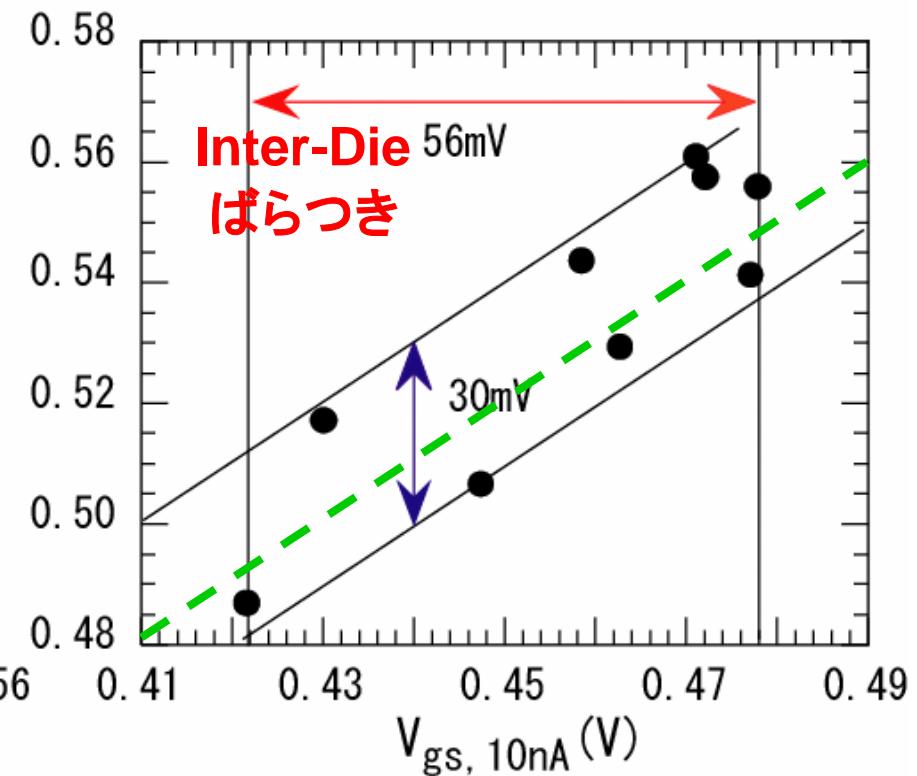
$V_{in}/2$ : Deviation from straight line determines intra-die variation

$V_{gs, 10nA}$ : Single MOSFET's inter-die variation

$L_{gate}=2.1\mu m$



$L_{gate}=0.6\mu m$



# Connection to process-parameter variation

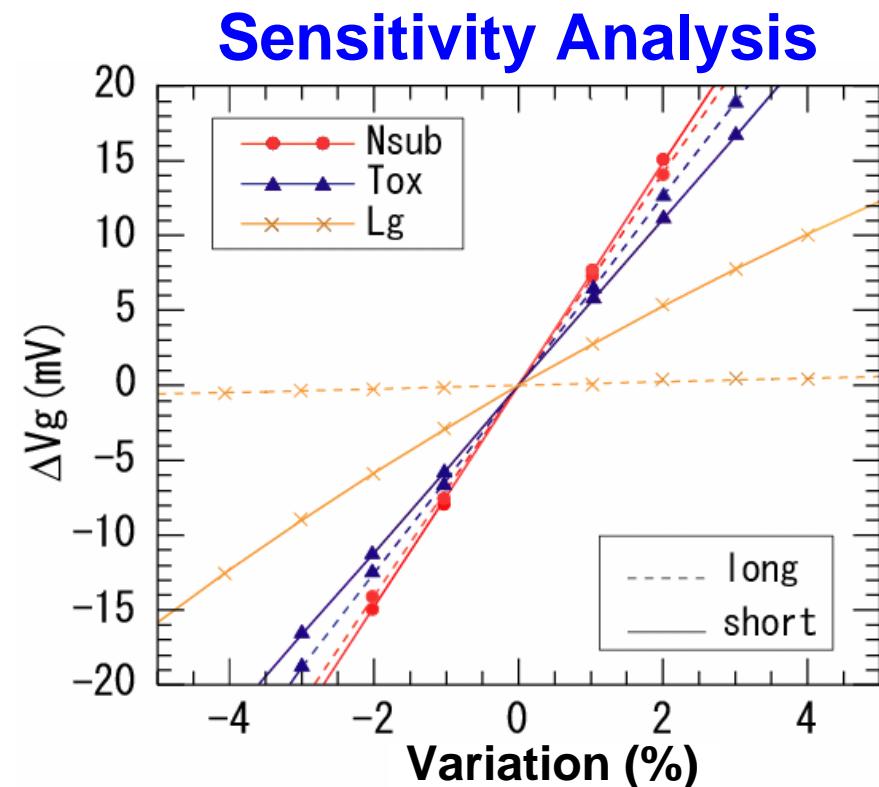
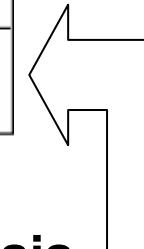
Deviation of process parameters from nominal values

	$\Delta N_{\text{sub}}$	$\Delta L_{\text{gate}}/0.6\mu\text{m}$	$T_{\text{ox}}$
Inter	1.2% / -7%	6.7% / -3.3%	1.4% / 0.7%
Intra	1%	3.8%	0

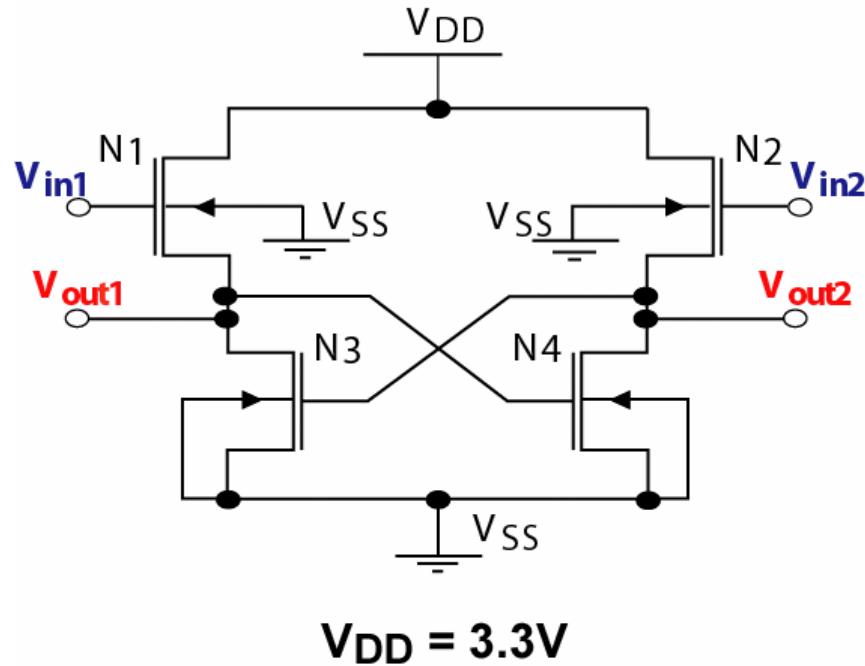
$\Delta V_g$  variations determined with cascode current source

	2.1 $\mu\text{m}$	0.6 $\mu\text{m}$
Inter	25.5mV	56mV
Intra	8.75mV	30mV

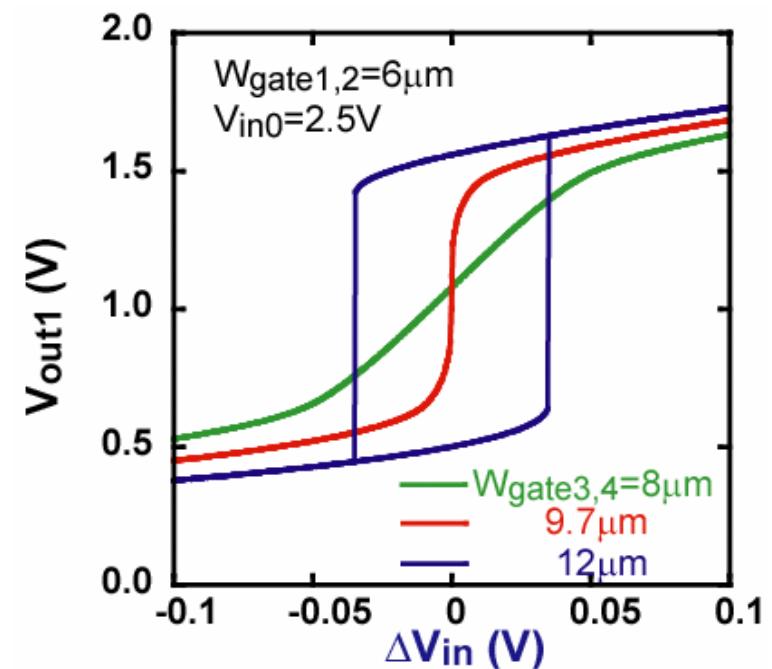
Sensitivity Analysis  
with HiSiM



# Differential amplifier stage



Function: to amplify  $V_{in}$  to  $V_{out}$ .



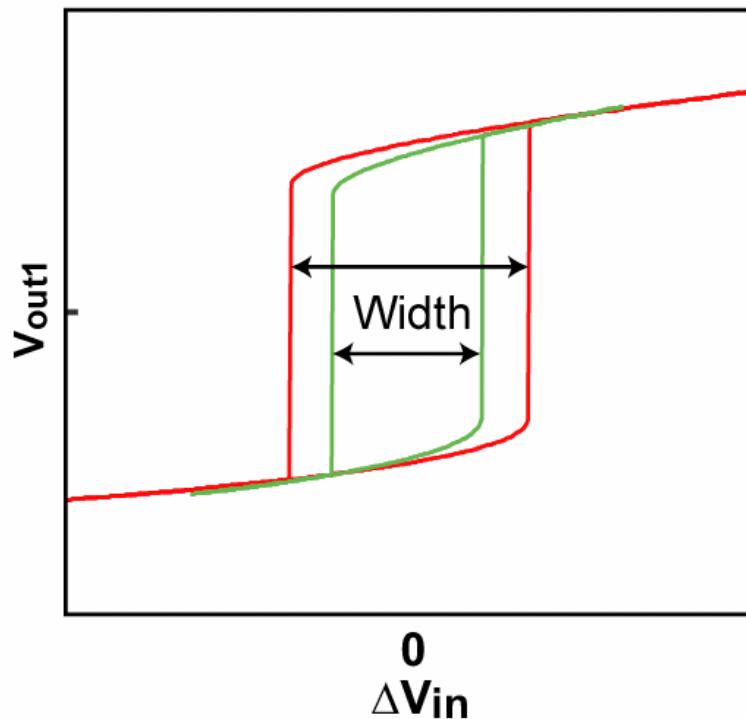
$$\Delta V_{in} = V_{in1} - V_{in2}$$

Appearance of a Hysteresis depends on the choice of channel width for N3 and N4

S. Matsumoto et al., CICC, p. 357, 2001.

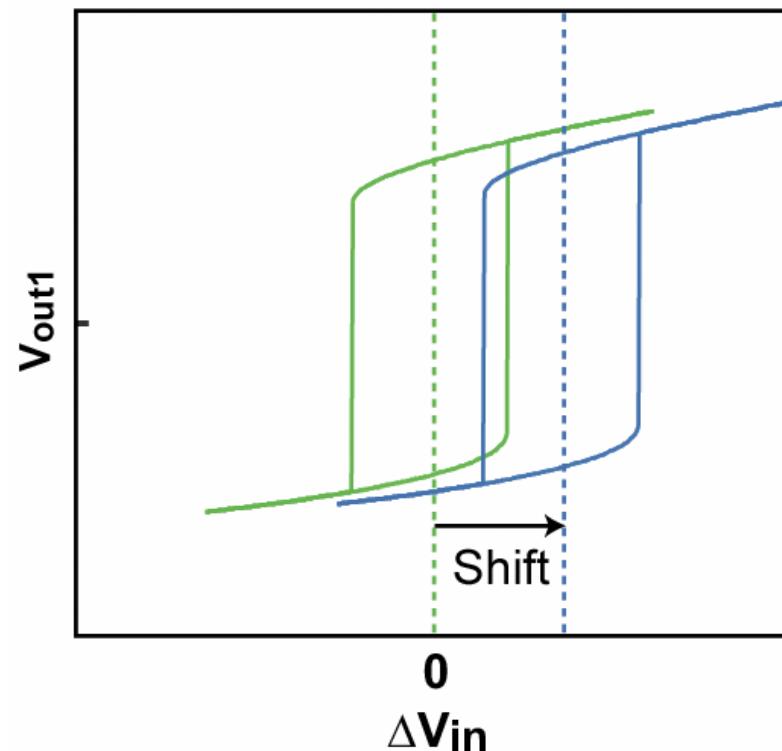
# Characteristic features of the hysteresis

Width Variation



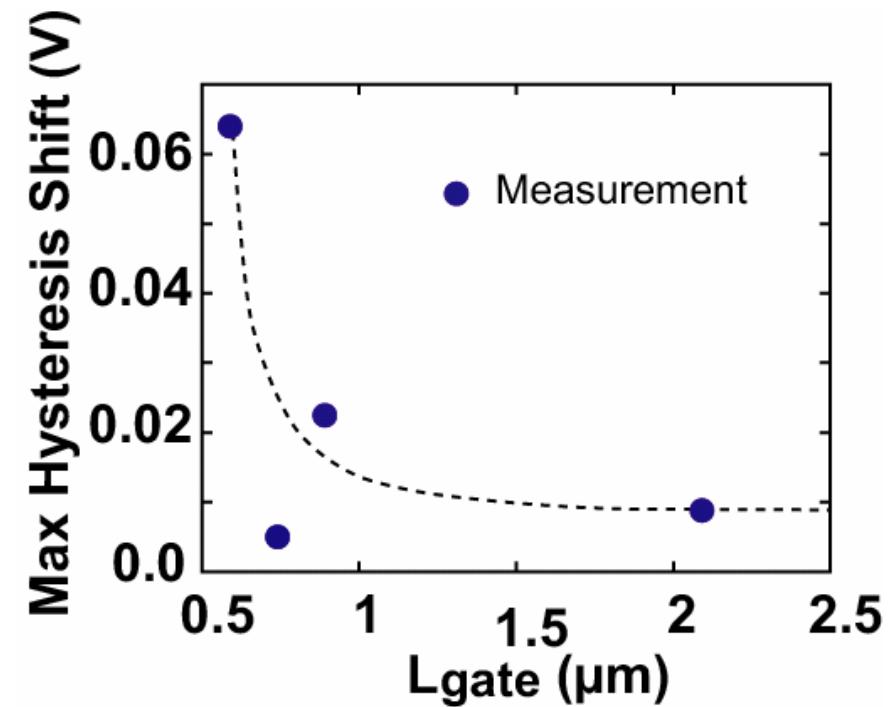
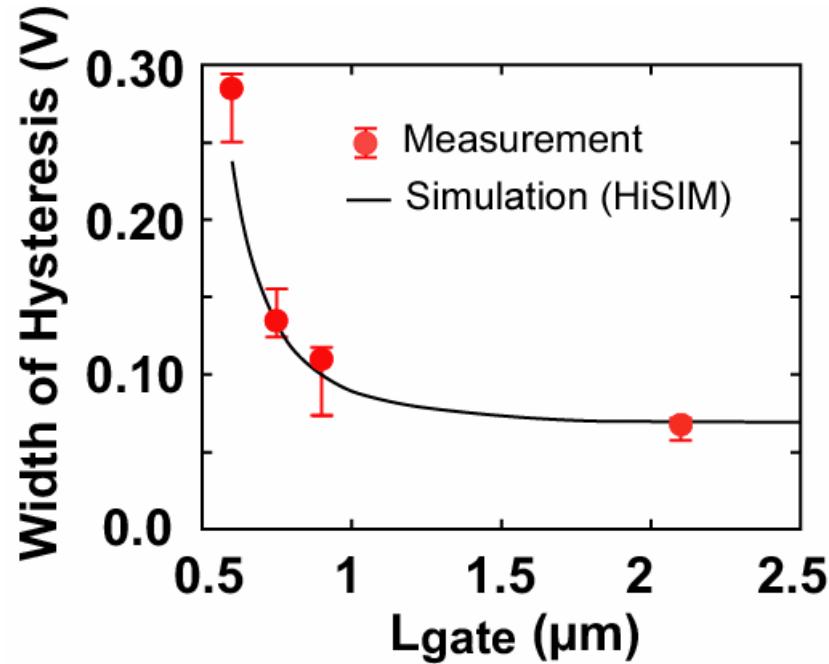
**Same change of parameters for all 4 transistors**

Shift Variation



**Difference in parameter change for the 4 transistors**

# Measured gate length dependence



# Separation of inter-die and intra-die variation

Case of same changes for all 4 transistors



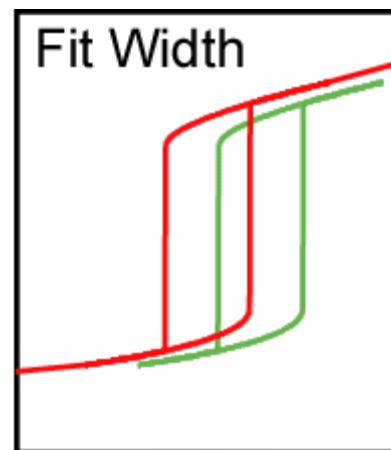
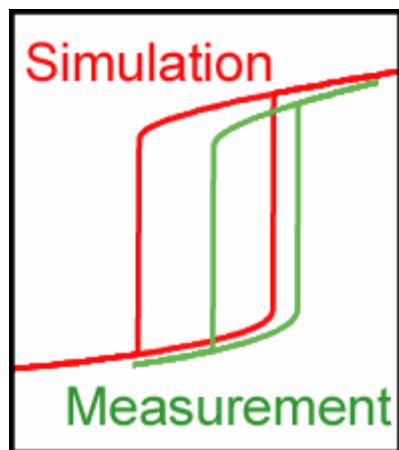
Case of different changes for each transistor



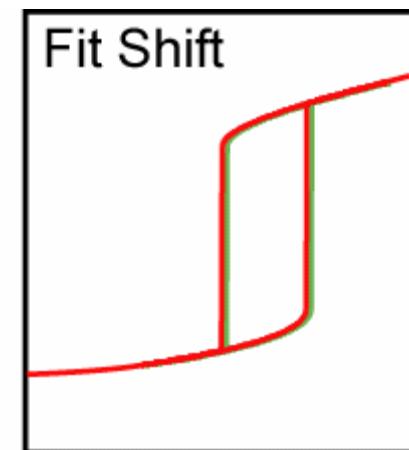
Inter-Die Variation

Intra-Die Variation

## Procedure for variation estimation



Inter-Die variation  
extraction



Intra-Die variation  
extraction

# Results of variation estimation

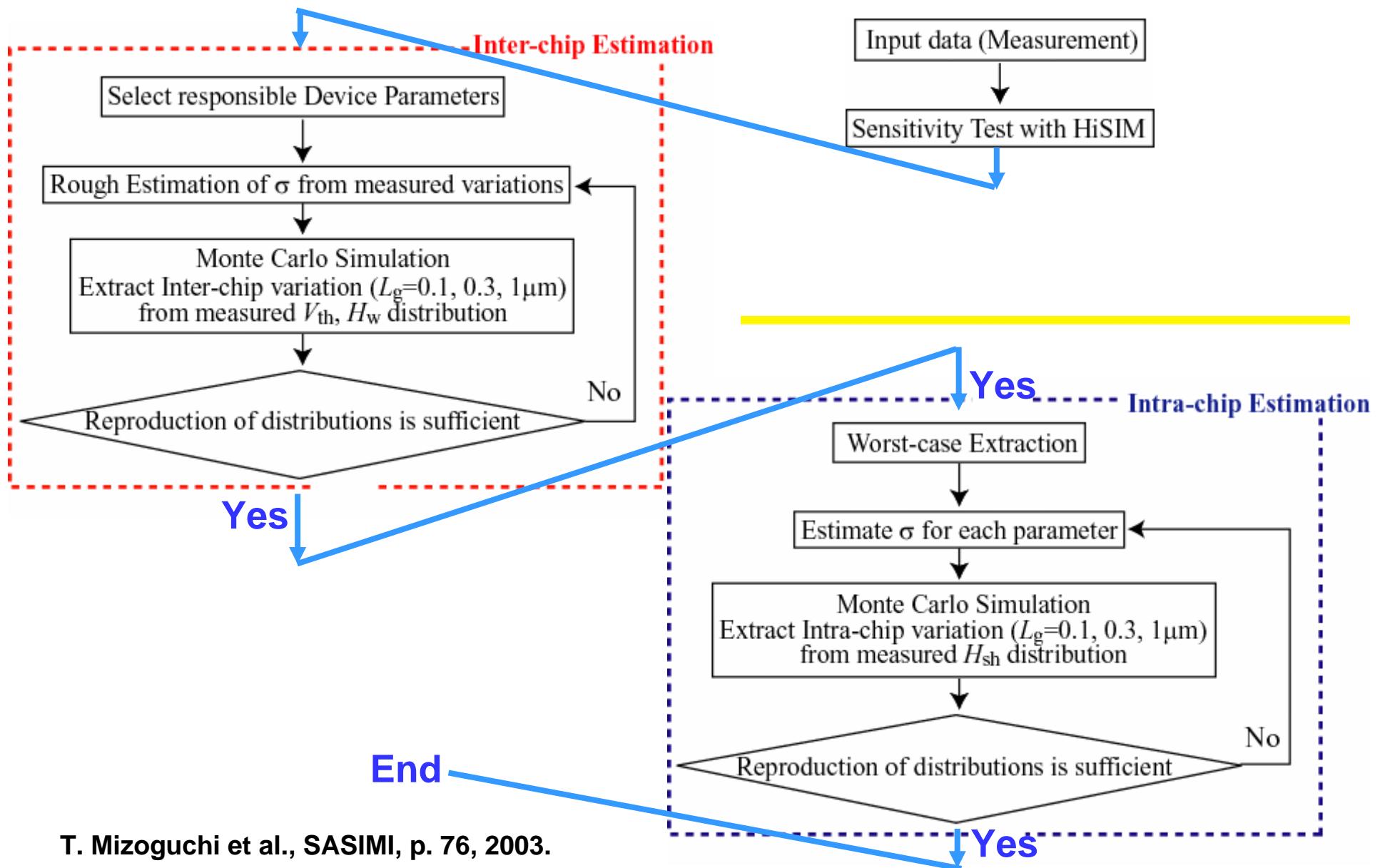
## Cascode Current Source

	$\Delta N_{\text{sub}}$	$\Delta L_{\text{gate}}/0.6\mu\text{m}$
Inter	7%	6.7%
Intra	1%	3.8%

## Differential-Amplifier Stage

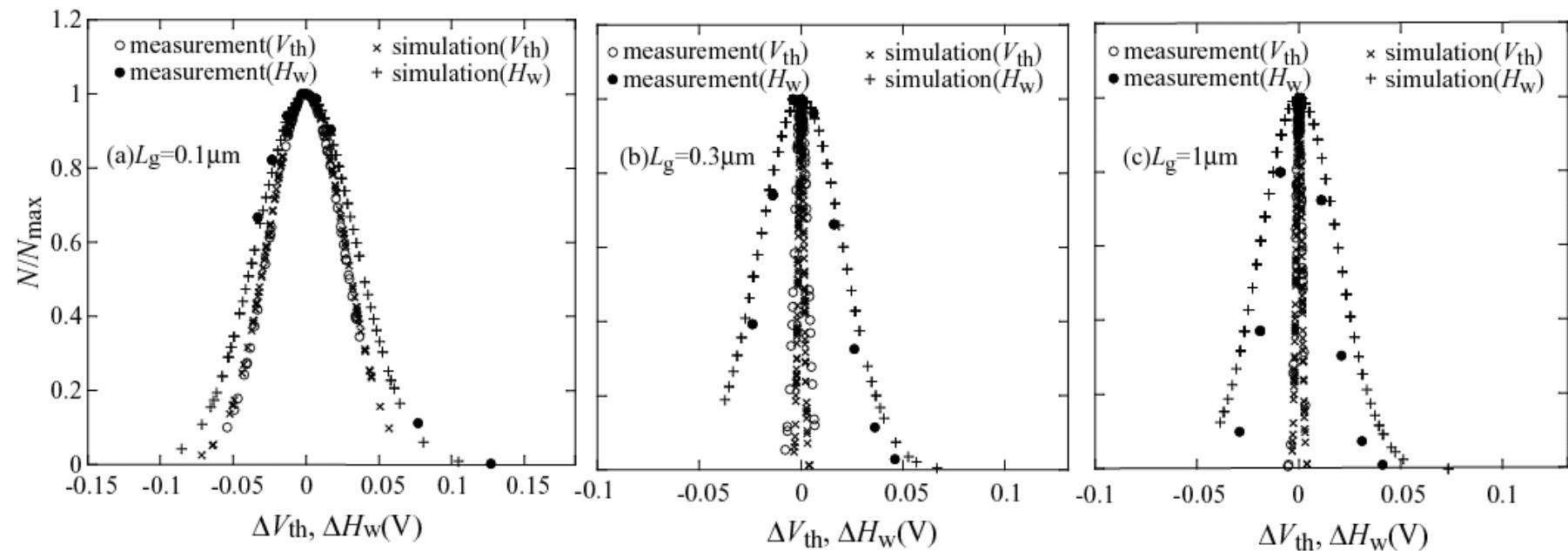
	$\Delta N_{\text{sub}}$	$\Delta L_{\text{gate}}/0.6\mu\text{m}$
Inter	5.9%	6.2%
Intra	2.3%	3.2%

# Extraction including distribution of variation



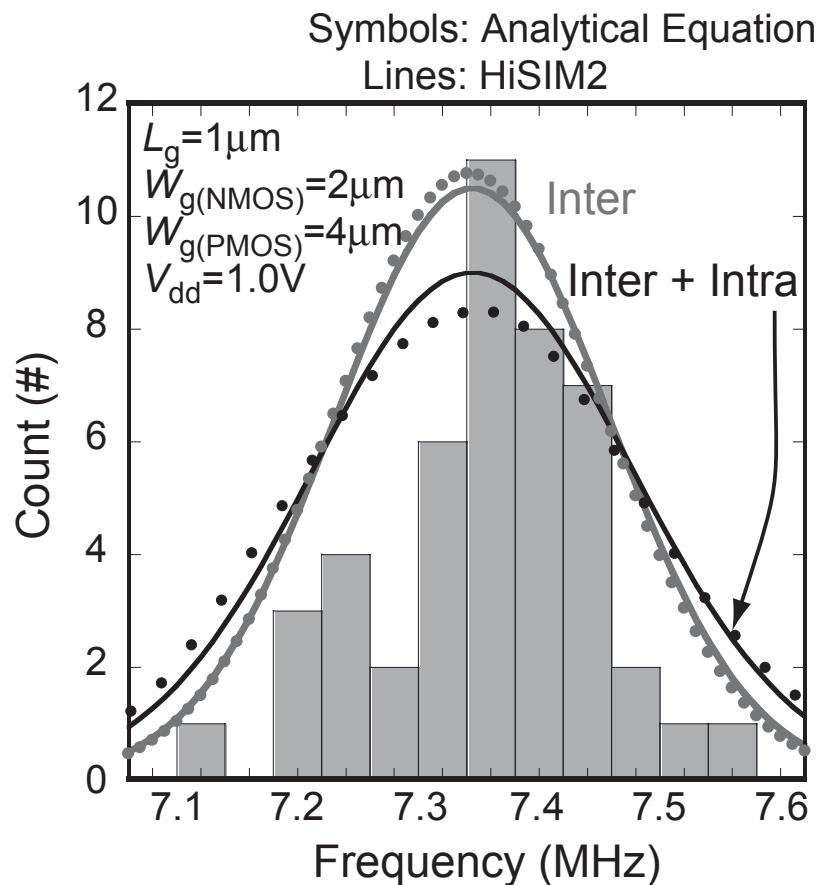
T. Mizoguchi et al., SASIMI, p. 76, 2003.

# Simulated and measured variation distribution

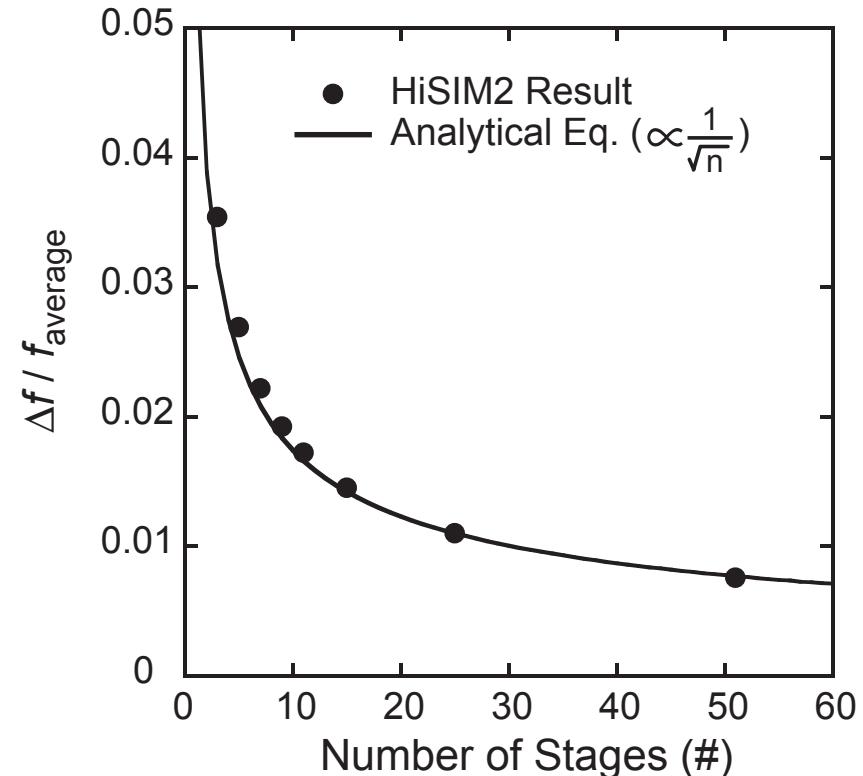


T. Mizoguchi et al., SASIMI, p. 76, 2003.

# Prediction of ring oscillator variation



51 stages



stage number  
dependence

# Conclusion

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- Increase of variation effects requires a physically correct circuit-simulation model, which accurately interrelates process-parameter variations and device-performance variations.
- Separation of inter-die and intra-die variations is difficult and facilitated by using suitable circuits in the variation extraction process.
- Prediction of circuit-performance variation becomes possible under these conditions.

# Presentation End

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Thank you for your attention !